

# IXO TWG January 2009 Boston

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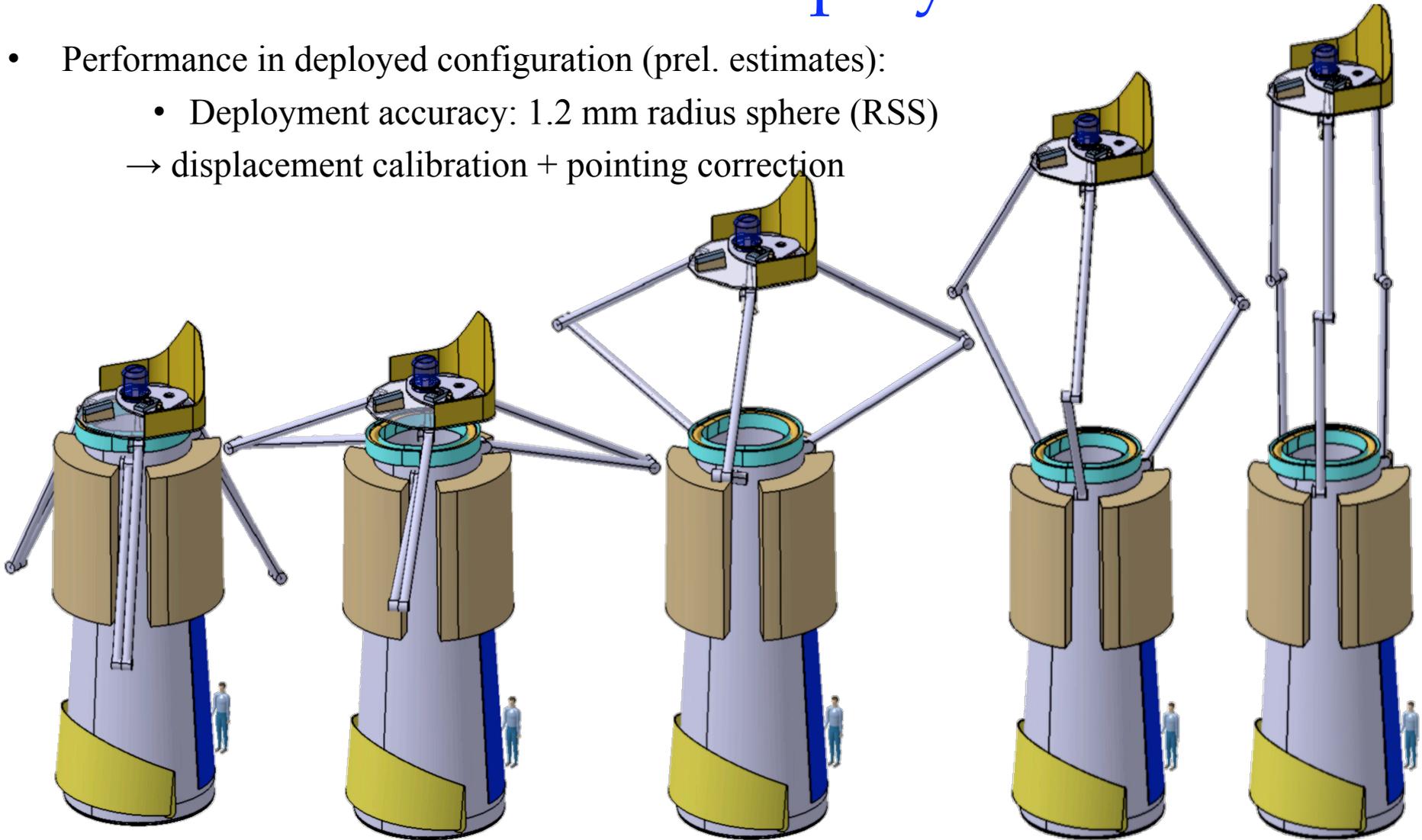
IXO System Studies and the IXO Optics  
The Si Pore Optics  
The predicted performance

# ESA+NASA - IXO System Studies and Optics

- **ESA CDF + NASA MDL - Optics Accomodation**
  - 20 m focal length – minimum required to get the specified effective area at  $> 6$  keV independent of the mirror technology.
  - Increase to 25 m focal length would improve the effective area  $> 10$  keV – by at least a factor of 2.
  - For the baseline Si optics design the full aperture radius  $0.25 \text{ m} < R < 1.9 \text{ m}$  is required to meet the specification of  $3 \text{ m}^2$  at 1 keV .
  - The aperture coverage required to meet the area specification for the baseline slumped glass optics design is slightly less.
  - Both studies allocate 1800 kg to the mirror module – this is limiting the low energy effective area for both technologies.
  - Both studies include a baffle/skirt to close off the extension volume – this stray light protection is required for the gratings.
- **IXO CDF telescope consolidation study (4th Feb → 16th Mar 2009)**

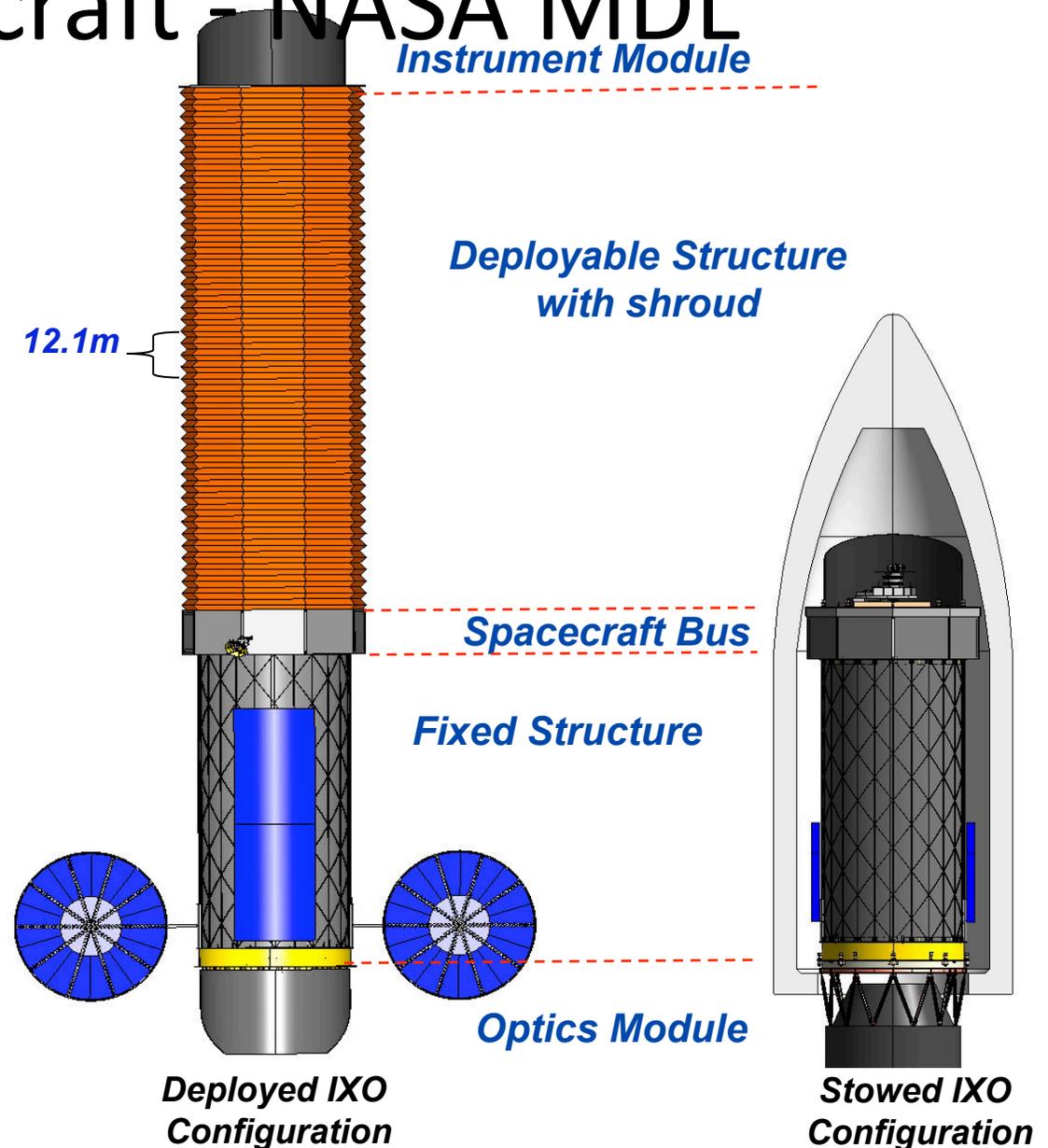
# IXO service module: deployment scheme

- Performance in deployed configuration (prel. estimates):
  - Deployment accuracy: 1.2 mm radius sphere (RSS)  
→ displacement calibration + pointing correction

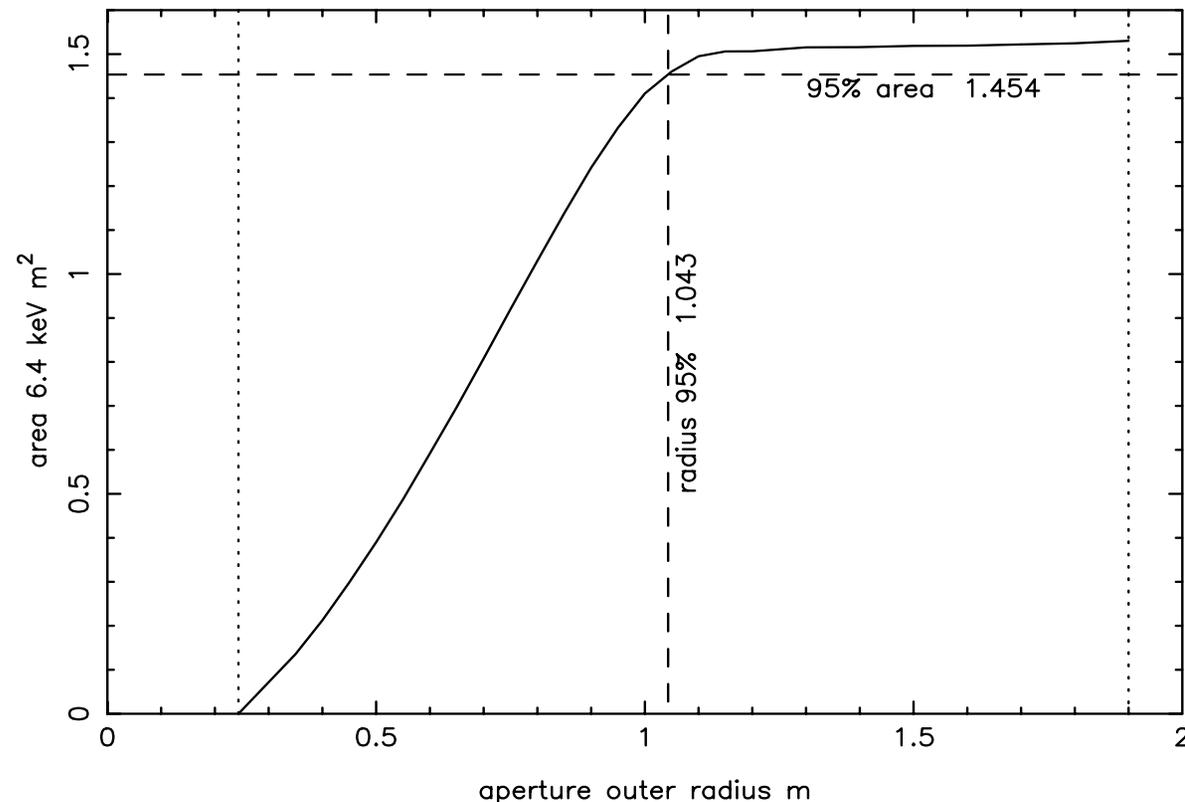


# IXO Spacecraft - NASA MDL

- Observatory Mass  
~6300 kg (including  
30% contingency)
- Launch on an Atlas V  
551 or Ariane V
- Direct launch into an  
800,000 km semi-  
major axis L2 orbit
- The observatory is  
deployed to achieve  
20 m focal length
- 5 year required

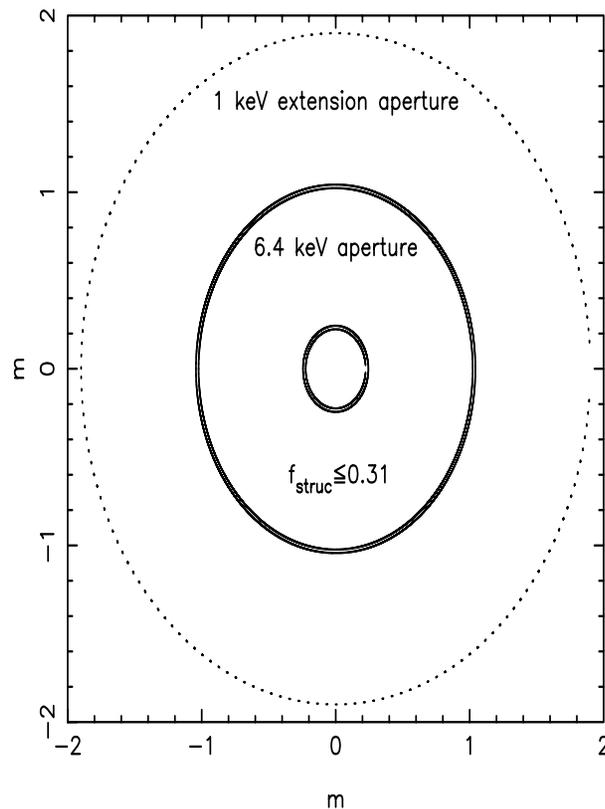


# Maximising the area at 6.4 keV



The minimum radius is set by the maximum axial length of available Si plates  
Increase in area with radius for Si pore optics with **NO support structure**

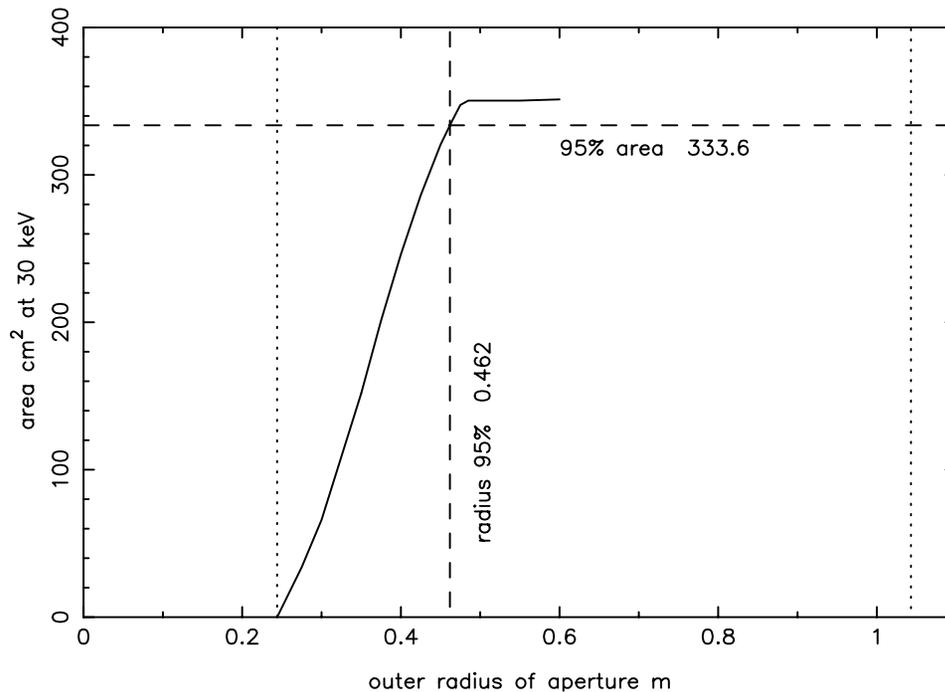
# You do need support structure!



If support obstruction is 31% then can achieve 1 m<sup>2</sup> at 6.4 keV.

Baseline design requires support obstruction of 55% which is conservative. This gives 0.65 m<sup>2</sup> at 6.4 keV.

# Similar story for 30 keV



Need multilayer coating  
on the inner shells.

An obscuration factor of  
55% will give 185 cm<sup>2</sup> at  
30 keV.

The CDF run 4th Feb → 16th Mar 2009 will revisit the area problem.

## Preliminary IXO pointing and optical bench stability requirements

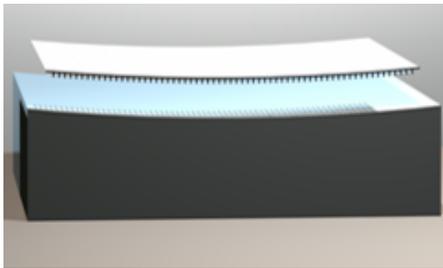
### Preliminary image quality error budget (HEW on-axis at 1.25 keV):

- Mirror module perf. under operation environment:	4.30 arcsec
- Optical design (conical approx.~ 3 arcsec)	
- Mirror figuring errors:	
- Mirror mid-frequencies errors & surface roughness:	
- Mirror plate alignment/confocality:	
-Mirror assembly system errors:	1.20 arcsec
- Assembly and integration	
- 1 g release	
- Thermal environment	
- Other (e.g. moisture release)	
- S/C pointing and optical bench distortions:	2.00 arcsec
- Events relative lateral measurement accuracy	
- Absolute longitudinal displacement errors	
- Margin: (including PSF sampling/detector pixel size)	1.00 arcsec
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Total (assuming RSS summation):	5.00 arcsec

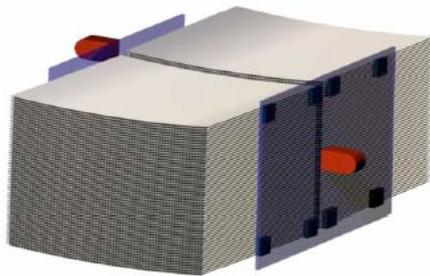
We need mirror modules with slightly better than 5 arc sec HEW to meet specification.

# Si Pore Optic based IXO mirror assembly

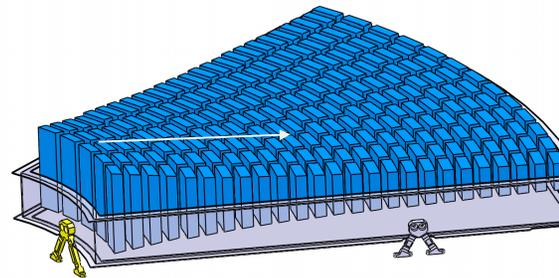
## Hierarchical elements



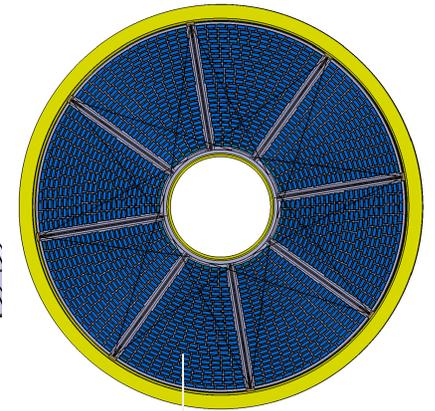
Mirror plates  
and stacks



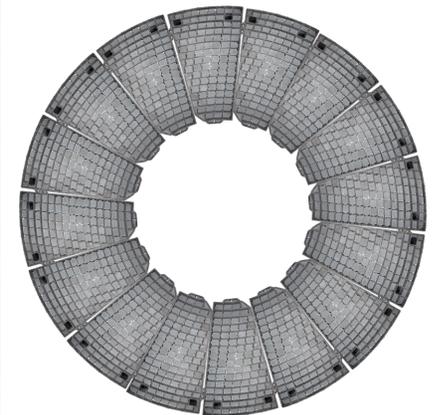
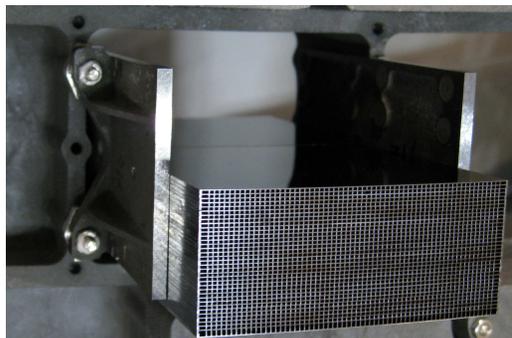
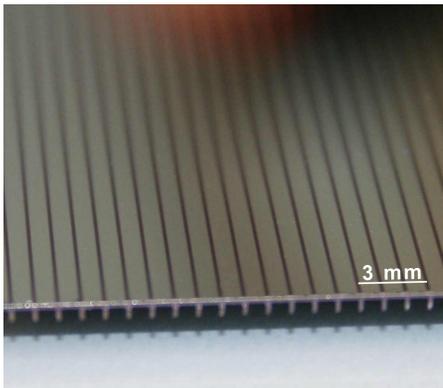
Mirror modules



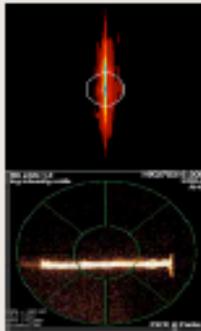
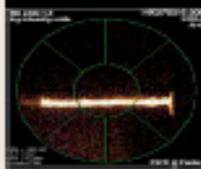
Petals



Optical bench



IXO Optics – Development & Production

Steps	Done		Next
Plate production	Industrial process	 	Reduce cost Different sizes
	Wedged, coated, non-conical		
	500 produced		
Stack production	Automated	 	Improve HEW
	Particle inspection, cleaning, bending, interferometry, stacking		
	200 produced		
Module production	Design to spec	 	
	Integration method to spec		
	Mounting method		
	4 produced		
Module validation & qualification	Synchrotron & beam testing in place	 	Environmental testing Focal plane testing
	Ruggedness assessment		
Petal production	Design to spec	 	
	1 produced		
Petal validation & qualification	First X-ray testing		Environmental testing Focal plane testing

Marco Biegersbergen, Max Colon, Marcus Bavdaz

### Stack production (1/9)

- Stacking robot 2007



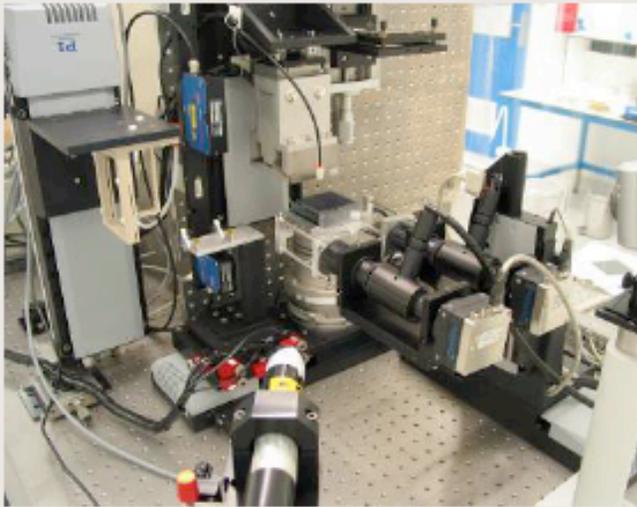
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## Stack production (2/9)

- Stacking robot, 3<sup>rd</sup> generation
  - Table top system, fully automated and remote controlled
  - Installed in cleanroom inside class 100 (10) tent
  - Based on a combination of standard semicon tools and newly developed units



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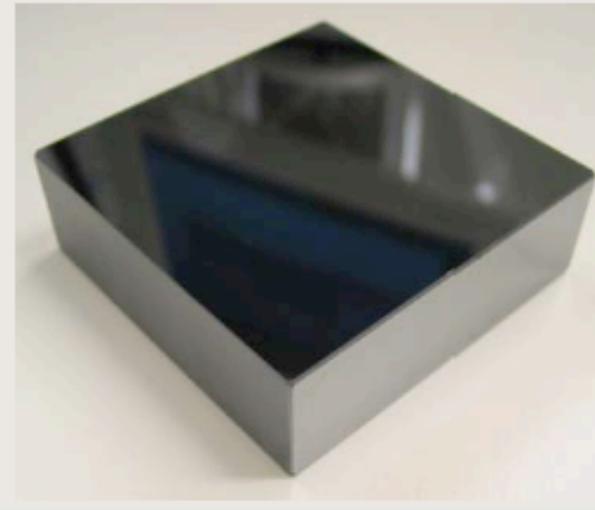
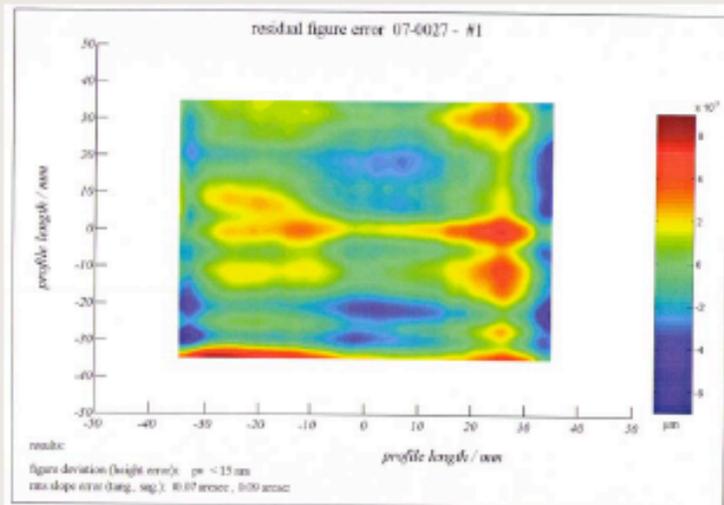
January 27, 2009

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Started operation 19<sup>th</sup> December 2008

## Stack production (3/9)

- Cylindrical mandrels from Zeiss
  - 0.1" rms residual error
  - Only figure (not roughness) important
  - need only 2 mandrels per ring (64 for IXO, not expensive)
  - Investigating now conical mandrels and double curvature



## Stack production (4/9)

- Stacking metrology in place
  - Metrology loop to X-ray data closed
- Particle measurement
  - custom particle detection system
  - calibration ongoing, special contaminated wafers will be ordered
- Plate-Plate alignment
  - microscopic / image analysis ( $< 5 \mu\text{m}$  accuracy)
  - force sensors (15 sensors /  $\text{cm}^2$ , 1 mN resolution)
  - front / back radii adjustable from 1900 to 2025 mm with  $0.03 \mu\text{m}$  accuracy)
  - Tip/tilt  $0.3 \mu\text{rad}$  resolution
- Figure
  - Twyman Green interferometer with CGH cylindrical nulling lens (FoV 100 mm)

Stack production (5/9)

Metrology concentrates on figure

bond quality by interferometry & microscopy

figure by interferometry

CGH

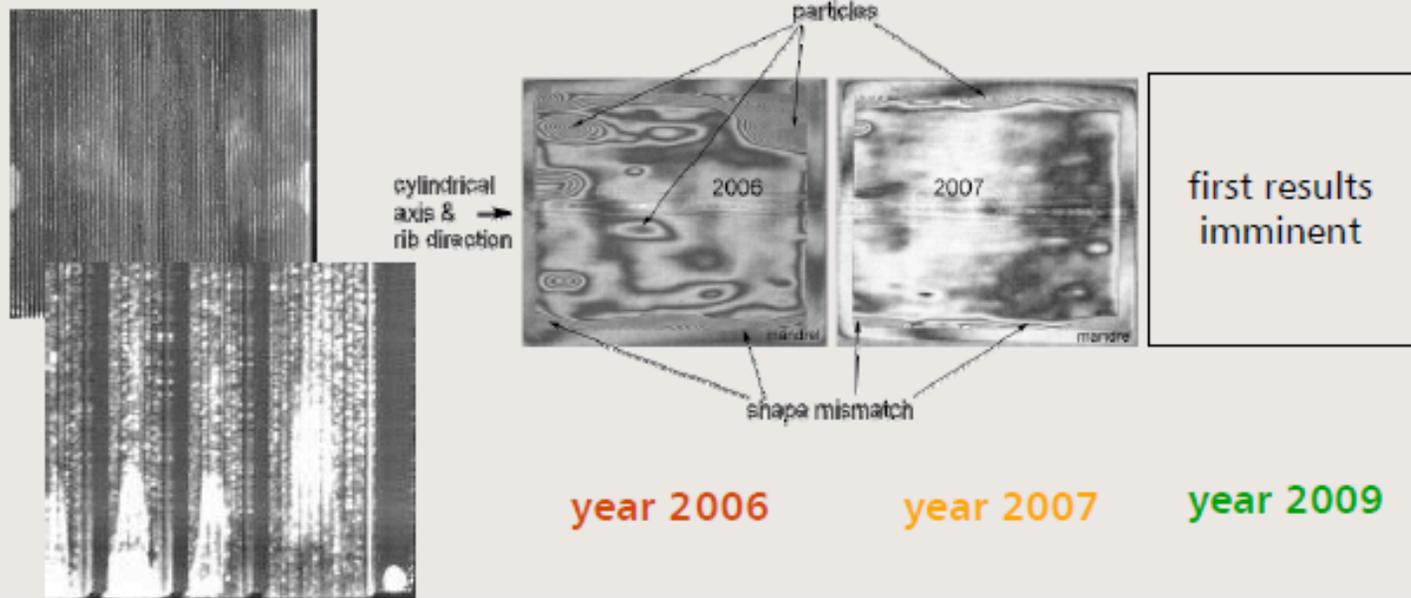
Shape match, before stacking, by microscopy

Base shape by interferometry

The image is a composite of several parts. At the top left is a photograph of a microscope measuring a component labeled 'CGH'. To the right is a 3D schematic of a stack of blue layers on a dark base. An orange circle highlights the interface between two layers, labeled 'bond quality by interferometry & microscopy'. A green oval highlights the top surface of the stack, labeled 'figure by interferometry'. Below this is another 3D schematic showing a white layer on a dark base, with red double-headed arrows indicating the gap between them, labeled 'Shape match, before stacking, by microscopy'. At the bottom left is a 3D schematic of a single layer on a dark base, labeled 'Base shape by interferometry'. At the bottom right is a 2x4 grid of interferometry images showing various patterns of light and dark spots.

## Stack production (6/9)

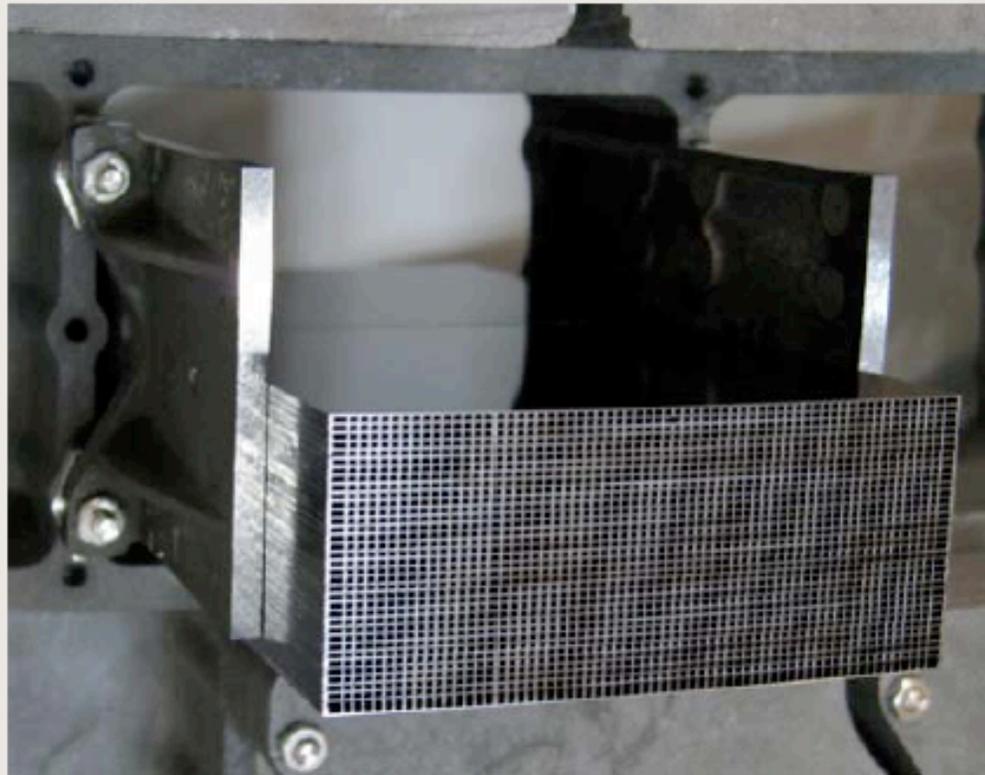
- Particle detection with custom system based on scattering
  - Difficult is detection on ribbed side
  - Current requirement (particles  $< 1 \mu\text{m}$ )
  - Final goal  $< 100 \text{ nm}$  (elastic deformation of silicon)



## Stack production (8/9)

- Pull tests in preparation (Q1 2009)
  - confirm bond strength values
  - study bond strength as function of process parameters
  - Note: so far (3 years) no bonded stack came apart, 2 modules mounted in petal since 2 years
- Environmental tests in preparation (Q2 2010)
  - **Vibration of stacks**
    - Need to perfect stacking, stacks still quite costly
    - So far no indication of problems:
      - Transporting stacks by courier and/or hand carrying
      - Mounting and dismounting at BESSY, PANTER and at KT
  - **Thermally cycled one HPO**
    - 100 h @ 200 deg C
    - No measurable degradation of figure of top surface

Module production (8/8)

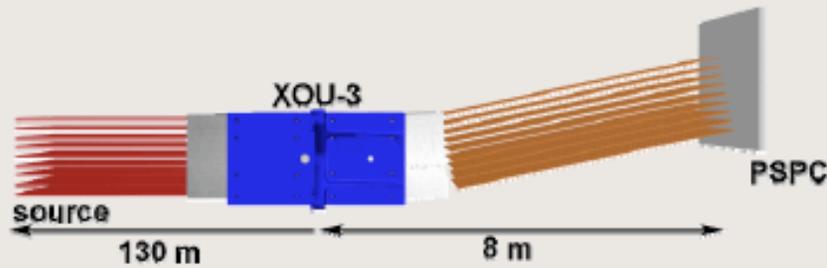


Module, mounted in petal prior to PANTER testing

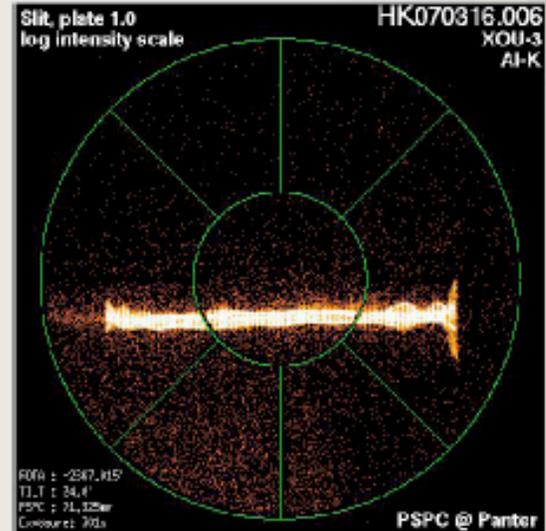
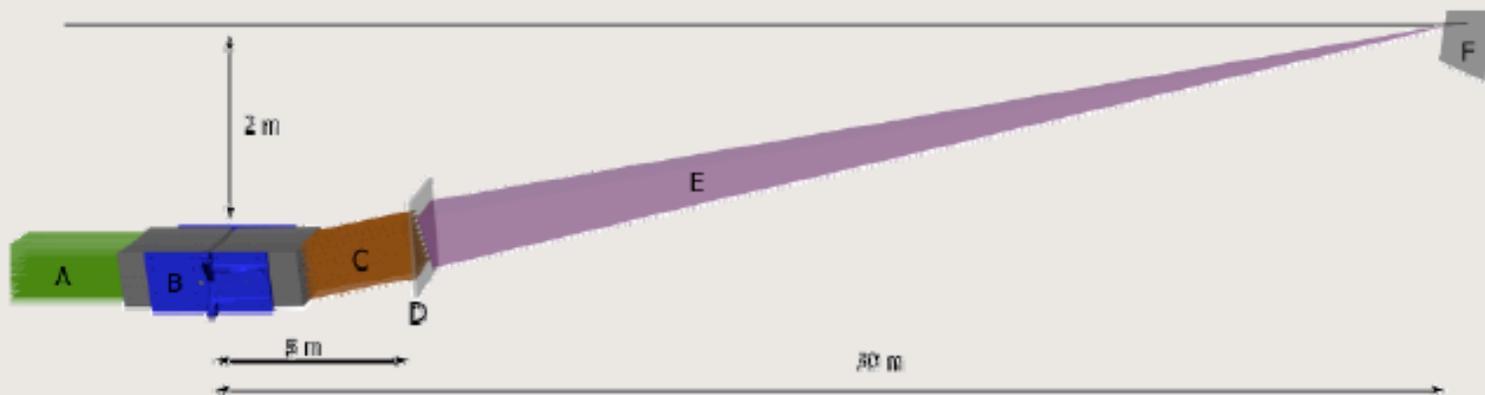
This stack has not got the full compliment of Si plates

Mirror module testing

- PANTER full beam (divergent)

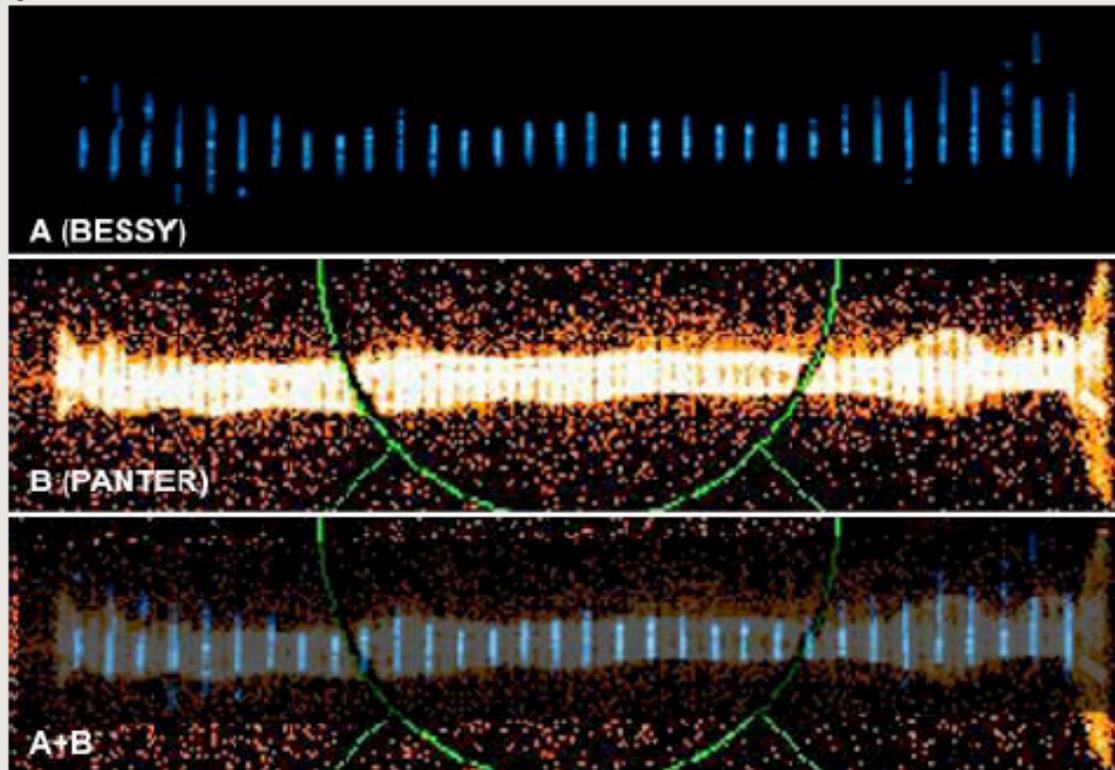


- BESSY pencil (50 $\mu$ m) beam



### Mirror module testing

- Repeated PANTER measurements at BESSY

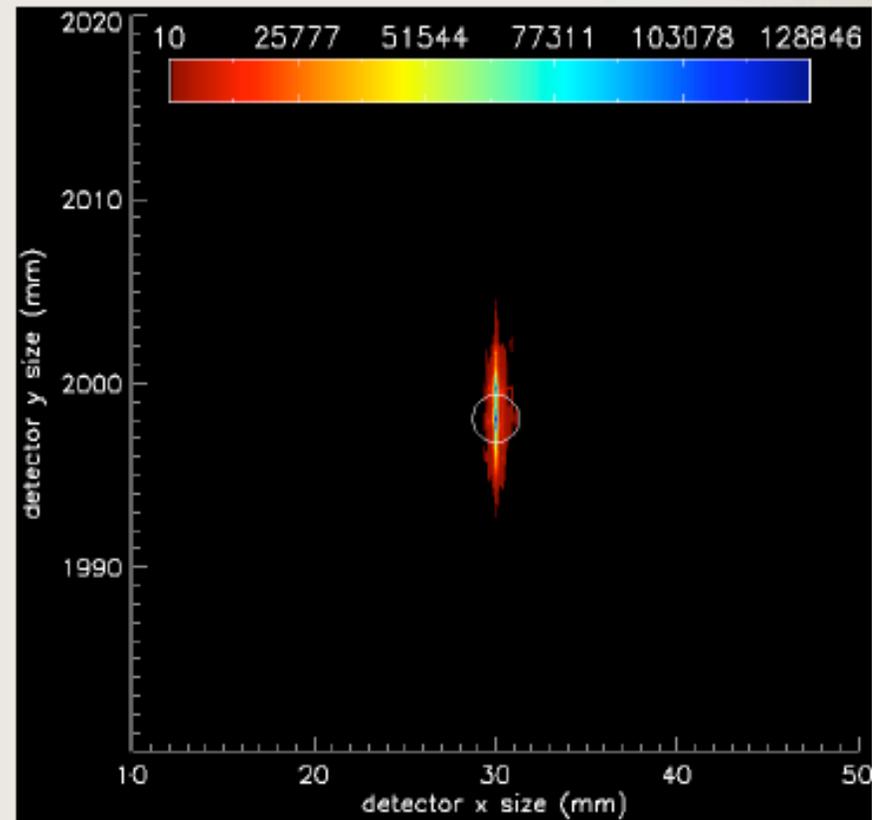


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Silicon Pore Optics

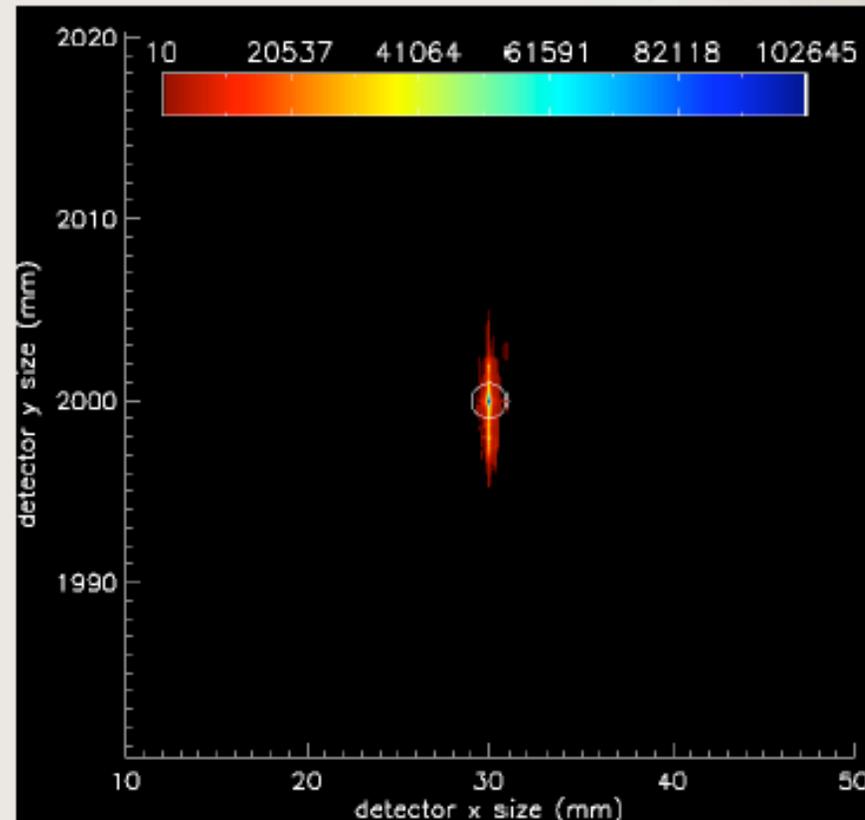
## Mirror module testing

- HEW 17" @ 50 m
  - double reflection
  - mounted optics
  - absolute
  - no subtraction
- Plates 1-4
  - full width
  - $A_{\text{col}} = 1.25 \text{ cm}^2$



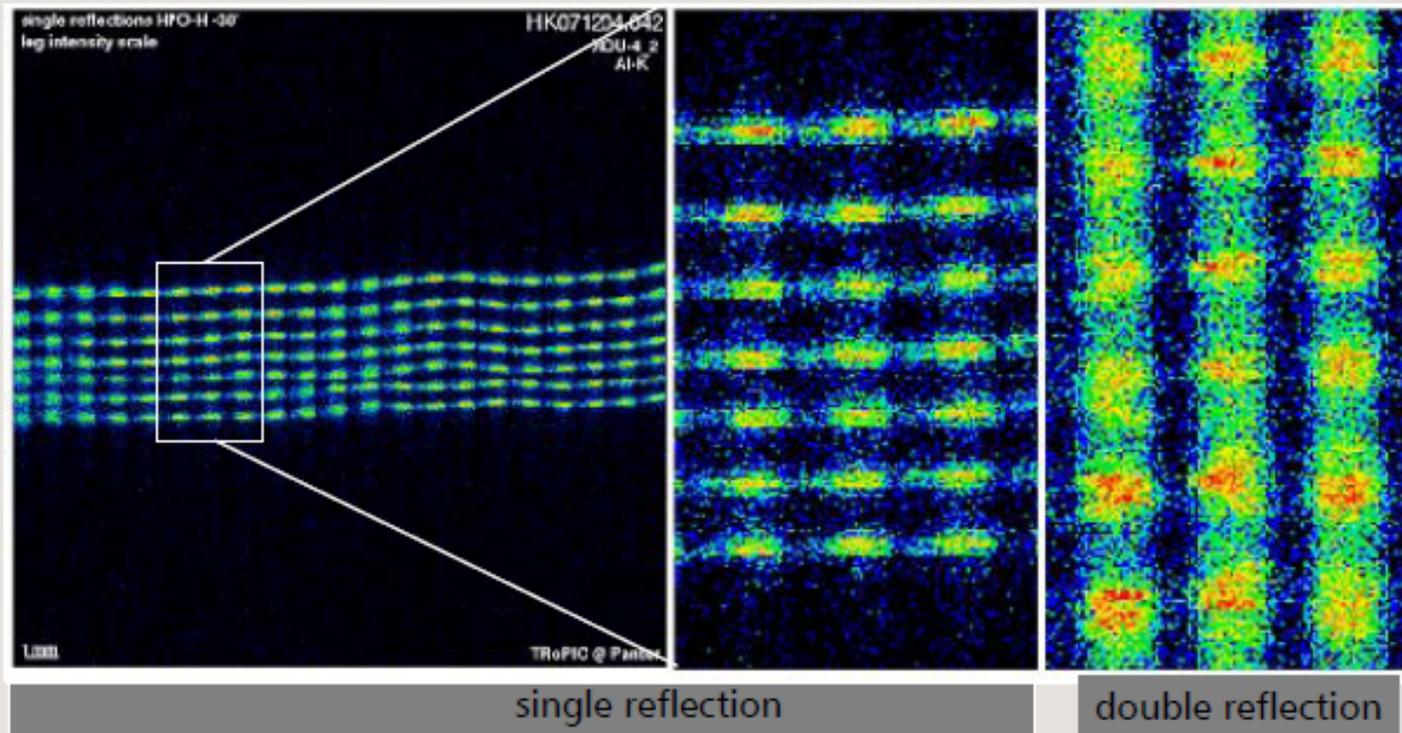
## Mirror module testing

- Remove known particle locations
- Select first two plates (larger bonded area)
  - double reflection
  - mounted optics
  - absolute
  - no subtraction
- Plates 1-2
  - full width
  - $A_{\text{col}} = 0.6 \text{ cm}^2$



### Mirror module testing

Expected spacing  $713.0 \mu\text{m}$ , measured spacing  $711.5 \mu\text{m}$



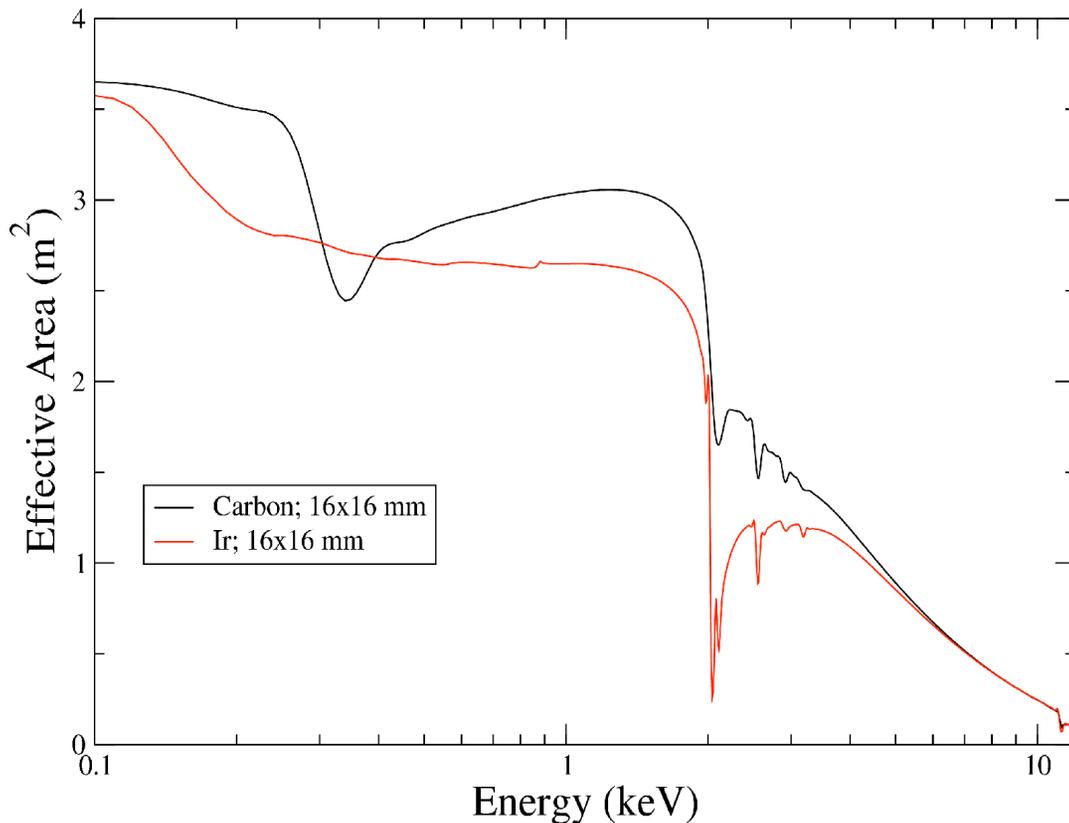
Have built and demonstrated first fully focussing XOU

## Conclusions

- Silicon Pore optics are close to TRL 4
  - Plates are mass produced by industry
  - Have mirror modules and a mounting method
  - Coating inside pores (Ir+C)
  - We are testing mounted optics in flight configuration
  
- Mass production of modules ramping up
  - industrial consortia are forming
  - co-locate plate production, coating and stacking in semicon fab
    - industrial stacking robot fits onto one optical table
    - production of one coated stack (45 plates) every 2 hours possible
  
- ESA funding for technology development is in place
  - ruggedization
  - figure improvement
  - industrialisation

all being addressed 2009-2010

# IXO mirror assembly: performance estimate baseline CDF study



**Without C overcoating:**

$A_{\text{eff}}(1.25 \text{ keV}) \sim 2.6 \text{ m}^2$

$A_{\text{eff}}(6.00 \text{ keV}) \sim 0.65 \text{ m}^2$

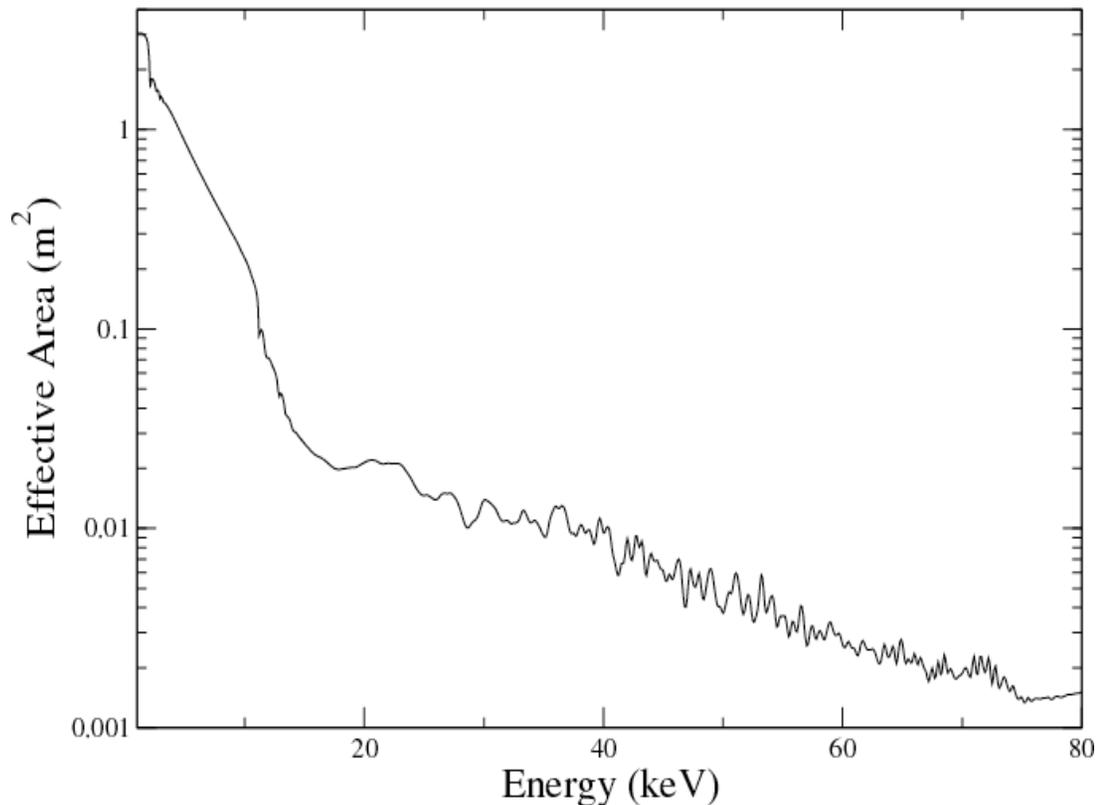
**With 90 Angstrom C overcoating:**

$A_{\text{eff}}(1.25 \text{ keV}) \sim 3.0 \text{ m}^2$

$A_{\text{eff}}(6.00 \text{ keV}) \sim 0.65 \text{ m}^2$

**To achieve the  $3\text{m}^2$   $A_{\text{eff}}$  at 1.25 keV requirements, the mirror modules shall be covered with a C overcoating**

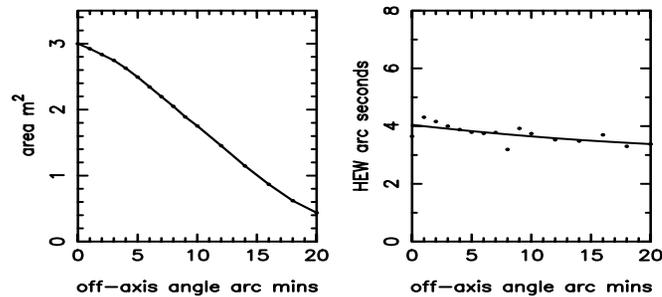
# IXO mirror assembly: performance estimate baseline CDF study



**With JAXA/ISAS multilayer design (courtesy H. Kunieda):**

**$A_{\text{eff}}(30 \text{ keV}) \sim 150 \text{ cm}^2$**

# Off-axis response of Si Pore Optics

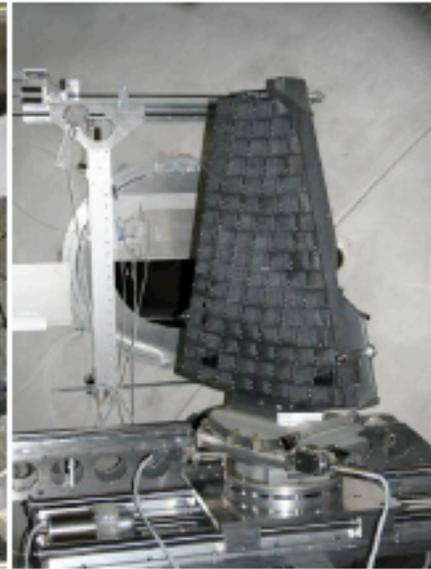
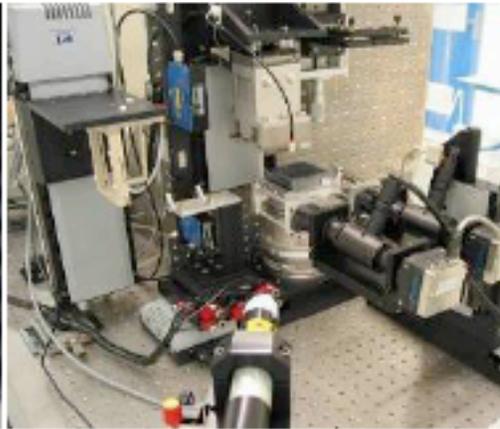
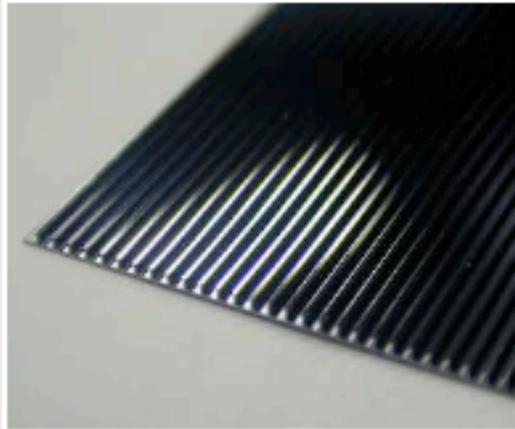


Ray tracing predictions – includes conical approximation and a small figure error

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Silicon Pore Optics

## Silicon Pore Optics



# Issues/Actions/Recommendations

## IXO TWG January 2009 Boston

- Extension baffle/skirt evaluation/optimization – stray light
- Front baffle for mirror assembly – stray light transmitted through mirror system
- Grating spectrometer – specify sub-aperture PSF needed to achieve high spectral resolution
- Upgrade of test/calibration facilities and use of BESSY, SPring-8...
- Repeat the optical design for both Si Pore and slumped glass technologies using common criteria/data/software
- Full comparison/trade-off of Si Pore vs. slumped glass technologies
- Major push to demonstrate a mirror module with  $\sim 5$  arc seconds HEW (Si HPO or  $\sim 3$  nested slumped glass pairs)
- Construct a full error budget for the angular resolution – as far as possible common to both mirror technologies

# Mirror Baffle

- Preliminary studies have been done
  - Si pore optics can incorporate a baffle integral to the front (parabola) plates
  - This solution is not possible for the inner most (small radii) modules
  - There will be a residual enhancement of diffuse sky background maybe up to a factor of 2 – needs a dedicated study for both the Si pore and slumped glass technologies

## Mirror module testing future

- Both BESSY and PANTER will be upgraded 2009/2010
  - Measure in focal plane of optics
  - **BESSY** change energy from 3 keV to 1 keV
    - larger grazing incidence angle
    - 20 m tube can be accommodated
  - **PANTER** upgrade more complicated
    - requires synchronization with eRosita and Symbol-X activities

